Docket No.: M4065.0706/P706 (PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Jiutao Li et al. Group Art Unit: 1795

Application No.: 10/712,106 Examiner: Rodney Glenn McDonald

Filed: November 14, 2003 Confirmation No.: 8216

For: SILVER SELENIDE SPUTTERED FILMS AND Allowed: April 22, 2010

METHOD AND APPARATUS FOR CONTROLLING DEFECT FORMATION IN SILVER SELENIDE SPUTTERED FILMS

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

MS Issue Fee

Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Applicants agree in part with the Examiner's statement of reasons for allowance in that the prior art of record fails to anticipate or render obvious the claimed invention. However, Applicants note that the Examiner's statement fails to address all limitations of all of the allowed claims. For example, certain claim limitations were not discussed in the Examiner's reasons for allowance, including those in the dependent claims, each of which defines a unique combination of features not shown or suggested by the prior art, providing additional reasons for allowance of each claim.

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Applicants submit that the scope of the claims should be interpreted based on the actual language of the allowed claims, and no further limitation of the claims should be inferred from the Examiner's Statement of Reasons For Allowance.

Dated: July 21, 2010

Respectfully submitted,

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